

"RESPONSE UNDER 37 CFR 1.116-EXPEDITED PROCEDURE EXAMINING

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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

HIROYUKI YANO, ET AL.

SERIAL NO: 09/531,163

FILED: MARCH 17, 2000

: GROUP ART UNIT: 1765

: EXAMINER: DEO, DUY VU NGUYE

FOR: AQUEOUS DISPERSION,
AQUEOUS DISPERSION FOR
CHEMICAL MECHANICAL POLISHING
USED FOR MANUFACTURE OF
SEMICONDUCTOR DEVICES, METHOD
FOR MANUFACTURE OF
SEMICONDUCTOR DEVICES, AND
METHOD FOR FORMATION OF
EMBEDDED WIRING

AMENDMENT AND REQUEST FOR RECONSIDERATION

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

Responsive to the Office Action of October 2, 2003, Applicants respectfully request reconsideration of the above-identified application in view of the following amendment and remarks.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Basis for the Amendment begins on page 7 of this paper and includes an attached replacement sheet.

Request for Reconsideration begins on page 8 of this paper.